Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Previously Presented) A method of manufacturing a mask comprising:
attaching to a frame having an opening a screen plate having a plurality of
penetrating holes arranged to form a mask pattern such that the penetrating holes are
positioned within the opening, the penetrating holes set to perpendicularly connect holes
formed in opposite surfaces of the screen plate;

forming a groove on at least one of a surface of the frame facing the screen plate and a surface of the screen plate facing the frame; and

utilizing the groove to form a flow path between the frame and the screen plate.

- 2. (Original) The manufacturing method of the mask as defined in claim 1, wherein at least part of the groove is formed around the opening.
- 3. (Previously Presented) The manufacturing method of the mask as defined in claim 1,

 wherein the frame and the screen plate are joined by anode coupling.
- 4. (Previously Presented) The manufacturing method of the mask as defined in claim 2,
 - wherein the frame and the screen plate are joined by anode coupling.
- 5. (Previously Presented) The manufacturing method of the mask as defined in claim 1, wherein the steps of forming the screen plate includes:

forming the penetrating holes in a silicon wafer; and cutting the silicon wafer into a shape corresponding to the screen plate.

6. (Previously Presented) The manufacturing method of the mask as defined in claim 1, further comprising:

forming a magnetic film over the screen plate.

7. (Previously Presented) The manufacturing method of the mask as defined in claim 1, wherein:

a plurality of the screen plates are attached to the frame;
the frame has a plurality of the openings; and
each of the screen plates is attached to corresponding one of the openings.

8. (Previously Presented) The manufacturing method of the mask as defined in claim 7, further comprising:

polishing surfaces of the screen plates attached to the frame to have a uniform height.

9. (Previously Presented) A mask comprising:

a frame having an opening; and

a screen plate attached to the frame and having a plurality of penetrating holes arranged to form a mask pattern, the penetrating holes set to perpendicularly connect holes formed in opposite surfaces of the screen plate, wherein:

the screen plate is attached to the frame such that the penetrating holes are positioned within the opening;

a groove is formed on at least one of a surface of the frame facing the screen plate and a surface of the screen plate facing the frame; and

the groove is utilized to form a flow path between the frame and the screen plate.

10. (Original) The mask as defined in claim 9, wherein at least part of the groove is formed around the opening.

- 11. (Previously Presented) The mask as defined in claim 9, wherein the frame and the screen plate are joined by anode coupling.
- 12. (Previously Presented) The mask as defined in claim 10, wherein the frame and the screen plate are joined by anode coupling.
- 13. (Previously Presented) The mask as defined in claim 9, wherein a magnetic film is formed over the screen plate.
 - 14. (Previously Presented) The mask as defined in claim 9, wherein:a plurality of the openings are formed in the frame;a plurality of the screen plates are attached to the frame; andeach of the screen plates is attached to corresponding one of the openings.
- 15. (Previously Presented) The mask as defined in claim 14, wherein surfaces of the screen plates attached to the frame are polished to have a uniform height.
- 16. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 9; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

17. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 10; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

18. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 11; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

19. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 12; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

20-21. (Canceled)

22. (Previously Presented) A method of manufacturing a mask comprising:

attaching to a frame having an opening a screen plate having a plurality of

penetrating holes arranged to form a mask pattern such that the penetrating holes are

positioned within the opening, the penetrating holes set to be tapered;

forming a groove on at least one of a surface of the frame facing the screen plate and a surface of the screen plate facing the frame; and

utilizing the groove to form a flow path between the frame and the screen plate.

- 23. (Original) The manufacturing method of the mask as defined in claim 22, wherein at least part of the groove is formed around the opening.
- 24. (Previously Presented) The manufacturing method of the mask as defined in claim 22, wherein the frame and the screen plate are joined by anode coupling.

- 25. (Previously Presented) The manufacturing method of the mask as defined in claim 23, wherein the frame and the screen plate are joined by anode coupling.
- 26. (Previously Presented) The manufacturing method of the mask as defined in claim 22, wherein the steps of forming the screen plate includes:

forming the penetrating holes in a silicon wafer; and cutting the silicon wafer into a shape corresponding to the screen plate.

27. (Previously Presented) The manufacturing method of the mask as defined in claim 22, further comprising:

forming a magnetic film over the screen plate.

28. (Previously Presented) The manufacturing method of the mask as defined in claim 22, wherein:

a plurality of the screen plates are attached to the frame;
the frame has a plurality of the openings; and
each of the screen plates is attached to corresponding one of the openings.

29. (Previously Presented) The manufacturing method of the mask as defined in claim 28, further comprising:

polishing surfaces of the screen plates attached to the frame to have a uniform height.

30. (Previously Presented) A mask comprising:

a frame having an opening; and

a screen plate attached to the frame and having a plurality of penetrating holes arranged to form a mask pattern, the penetrating holes set to be tapered, wherein:

the screen plate is attached to the frame such that the penetrating holes are positioned within the opening;

a groove is formed on at least one of a surface of the frame facing the screen plate and a surface of the screen plate facing the frame; and

the groove is utilized to form a flow path between the frame and the screen plate.

- 31. (Original) The mask as defined in claim 30, wherein at least part of the groove is formed around the opening.
- 32. (Previously Presented) The mask as defined in claim 30, wherein the frame and the screen plate are joined by anode coupling.
- 33. (Previously Presented) The mask as defined in claim 31, wherein the frame and the screen plate are joined by anode coupling.
- 34. (Previously Presented) The mask as defined in claim 30, wherein a magnetic film is formed over the screen plate.
 - 35. (Previously Presented) The mask as defined in claim 30, wherein:a plurality of the openings are formed in the frame;a plurality of the screen plates are attached to the frame; andeach of the screen plates is attached to corresponding one of the openings.
- 36. (Previously Presented) The mask as defined in claim 35, wherein surfaces of the screen plates attached to the frame are polished to have a uniform height.
- 37. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 30; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

38. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 31; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

39. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 32; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

40. (Original) A method of manufacturing an electro-luminescence device comprising:

forming a film of a light emitting material using the mask as defined in claim 33; and

cooling the mask by causing a fluid to flow through the flow path of the mask, in the step of forming a film of a light emitting material.

41-42. (Canceled)